

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	8	US-3974382-\$ DID. OR US-4402600-\$ DID. OR US-5530616-\$ DID. OR US-5656093-\$ DID.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/30 15:49
S2	2	("6217655").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/12/29 19:07
S3	2	("5982607").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/12/29 19:13
S4	5	pimple adj plate	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/29 19:13
S5	13462	((250/492.2) or (250/440.11) or (361/234) or (279/128) or (279/3) or (248/683) or (355/53) or (355/72) or (355/73) or (355/75) or (355/76) or (378/34) or (378/20) or (378/177) or (378/187)).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/12/30 10:59
S6	2781	S5 and lithography	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/30 10:59
S7	2639	S6 and (mask or reticle or substrate)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/30 11:00
S8	316	S7 and (pliable or compliant or flexible or deformable)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/30 11:02

S9	21	("4480284" "4724510" "5166856" "5179498" "5191506" "5255153" "5324053" "5486974" "5486975" "5522131" "5532903" "5539179" "5560780" "5583736" "5631803" "5646814" "5691876" "5745331" "5764471" "5777838").PN. OR ("6117246").URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2004/12/30 12:13
S10	2	("5532903").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/12/30 14:59
S11	19	("3974382" "4610020" "5275683" "5382311").PN. OR ("5532903").URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2004/12/30 14:59
S12	11	("3993509" "4184188" "4384918" "4551192" "5532903" "5583736" "5764471" "5777838" "5851641" "5883778").PN. OR ("6215642").URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2004/12/30 15:11
S13	2	("6480260").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/12/30 15:49
S14	5	("4716299" "4749867" "5137349" "6118515").PN. OR ("6480260").URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2004/12/30 15:49
S15	70	("4184188" "4361643" "4384918" "4502094" "4599970" "4603466" "5117121" "5192371" "5376180" "5382311" "5447595" "5456756" "5463526" "5474614" "5528451" "5530616" "5531835" "5560780" "5583736").PN. OR ("5656093").URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2004/12/30 16:05
S16	36	("4502094" "4565601" "4724510" "4962441" "5104834" "5160152" "5191506" "5213349" "5267607" "5306895" "5315473" "5350479").PN. OR ("5530616").URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2004/12/30 16:21
S17	1	"4610020".PN.	USPAT; USOCR	OR	ON	2004/12/30 16:28

S18	1	"5382311".PN.	USPAT; USOCR	OR	ON	2004/12/30 16:28
S19	1	"3974382".PN.	USPAT; USOCR	OR	ON	2004/12/30 16:28
S20	13462	((250/492.2) or (250/440.11) or (361/234) or (279/128) or (279/3) or (248/683) or (355/53) or (355/72) or (355/73) or (355/75) or (355/76) or (378/34) or (378/20) or (378/177) or (378/187)).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/12/30 16:34
S21	2781	S20 and lithography	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/30 16:34
S22	2639	S21 and (mask or reticle or substrate)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/30 16:34
S23	316	S22 and (pliable or compliant or flexible or deformable)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/30 16:35
S24	2	S23 and bessel	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/30 16:37
S25	1	S20 and (bessel adj point)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/30 16:39
S26	36	(bessel adj point)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/30 17:00
S27	96	S20 and kinematic	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/30 17:00

S28	84	S27 and three	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/30 17:14
S29	54	kinematic and bessel	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/30 17:15
S30	54	kinematic and bessel	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/30 17:28
S31	3	kinematically and (bessel or bessell)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/12/30 17:29

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Search Results - Record(s) 1 through 2 of 2 returned.

1. Document ID: EP 1107066 A2

Using default format because multiple data bases are involved.

L1: Entry 1 of 2

File: EPAB

Jun 13, 2001

PUB-NO: EP001107066A2

DOCUMENT-IDENTIFIER: EP 1107066 A2

TITLE: Lithographic apparatus with mask clamping apparatus

PUBN-DATE: June 13, 2001

INVENTOR-INFORMATION:

NAME	COUNTRY
DONDERS, SJOERD NICOLAAS LAMBER	NL
VAN, EMPEL TJARKO ADRIAAN RUDOL	NL

INT-CL (IPC): G03 F 7/20

EUR-CL (EPC): G03F007/20

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2. Document ID: TW 504605 A, EP 1107066 A2, JP 2001196303 A, KR 2001061974 A,
US 6480260 B1

L1: Entry 2 of 2

File: DWPI

Oct 1, 2002

DERWENT-ACC-NO: 2002-123948

DERWENT-WEEK: 200337

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TITLE: Lithographic projector for imaging mask pattern onto substrates used during manufacture of integrated circuits includes mask table with mask compliant member that conforms to mask profile

INVENTOR: DONDERS, S N L; VAN EMPEL, T A R

PRIORITY-DATA: 1999EP-0204103 (December 3, 1999)

PATENT-FAMILY:

PUB-NO	PUB-DATE	LANGUAGE	PAGES	MAIN-IPC
<u>TW 504605 A</u>	October 1, 2002		000	G03F009/00
<u>EP 1107066 A2</u>	June 13, 2001	E	012	G03F007/20
<u>JP 2001196303 A</u>	July 19, 2001		009	H01L021/027
<u>KR 2001061974 A</u>	July 7, 2001		000	G03F007/20
<u>US 6480260 B1</u>	November 12, 2002		000	G03B027/42

INT-CL (IPC): A61 N 5/00; G03 B 27/42; G03 B 27/58; G03 B 27/60; G03 C 5/00; G03 F 7/20; G03 F 9/00; H01 L 21/027

BASIC-ABSTRACT:

NOVELTY - A lithographic projection has radiation system for supplying a projection beam of radiation, object table for holding a mask, second object table for holding a substrate, and projection system for imaging irradiated portions of the mask onto target portions of substrate. The mask table has compliant member(s) for holding the mask such that at least one member conform to the profile of the mask.

DETAILED DESCRIPTION - INDEPENDENT CLAIMS are also included for the following:

(A) a method of manufacturing a device using a lithographic projector involving providing a mask bearing a pattern to the first object table, providing a substrate with a radiation-sensitive layer to the second object table, and irradiating portions of the mask and imaging the irradiated portions onto the target portions of the substrate;

(B) a device manufactured by the process; and

(C) a mask table comprising compliant member (14). The mask is held during operation with the clamping device.

USE - The method is used for imaging mask pattern onto substrates during manufacture of integrated circuits, integrated optical systems, guidance and detection patterns for magnetic domain memories, liquid-crystal display panels, and thin-film magnetic heads.

ADVANTAGE - The members are compliant such that they accommodate flatness variations in the mask without deforming the mask.

DESCRIPTION OF DRAWING(S) - The figure shows a schematic view of an arrangement for supporting a mask using a compliant member.

Compliant members 14

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Term	Documents
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EP-1107066-A2	2
EP-1107066-\$..DID..PGPB,USPT,EPAB,JPAB,DWPI,TDBD.	2
(EP-1107066-\$..DID..).PGPB,USPT,EPAB,JPAB,DWPI,TDBD.	2

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